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Atty Docket No. NOVLP029/NVLS-000495 Application No.:

10/067,520

Information Disclosure Statement By Applicant

Applicant: Shrinivasan et al.

(Use Several Sheets if Necessary)

Filing Date February 5, 2002 Group 2811

U.S. Patent Documents

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Initial	No.	Patent No.	Date	Patentee	Class	class	Date
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Examiner		Document	Publication	Country or		Sub-	Trans	slation
Initial	No.	No.	Date	Patent Office	Class	class	Yes	No
Mr	B1	WO02/01947	01/31/02	WIPO				
	B2	WO01/46999	06/28/01	WIPO		1.		
	B3	WO01/33615	05/10/01	WIPO				
MK	B4	WO01/33613	05/10/01	WIPO				
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Other Documents

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Α	Worm et al., "Spray Member and Method for Using the Same," U.S. Publication No. US 2003/0049939, Pub Date: March 13, 2003, 42 Pages
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Form 449 (Modified)

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MK	A	Biberger et al., "High Pressure Processing Chamber for Semiconductor Substrate", Pub. No. US 2002/0046707 A1, Pub. Date: April 25, 2002, Appl. No.: 09/912,844, Filed: July 24, 2001, pp. 1-19.
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